Туре	Instrument	Location	Introduction	Operating Manual	Service Request	Technician Contact Information Deputy Contact Information	Examiner Contact Information	Charge
	E-Gun Evaporation System I	R133 in NTHU Lab	<u>Link Here</u>	<u>Download</u>	<u>Download</u>	Ms. Kuo TEL: 03 – 5742299 or NTHU Ext. 42299 E-mail : kuowenfeng@hotmail.com	Ms. Kuo TEL: 03 – 5742299 or NTHU Ext. 42299 E-mail: kuowenfeng@hotmail.com	<u>Link Here</u>
	E-Gun Evaporation System II		<u>Link Here</u>	Download	Download	(Deputy) Ms. Wu Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	Link Here
sloc	E-Gun Evaporation System III	NTHU Lab Cleanroom	<u>Link Here</u>	Download	Download	(Deputy) Ms. Kuo Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail: changcw@mx.nthu.edu.tw	Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail: changcw@mx.nthu.edu.tw	Link Here
Deposition Pocess Tools	Polymer Deposition System (PDS)		<u>Link Here</u>	Download	Download	(Deputy) Ms. Wu Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	<u>Link Here</u>
Deposit	SAMCO PECVD System	NTHU Lab Cleanroom	Link Here	Download	Download	(Deputy) Mr. Sung Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	<u>Link Here</u>
	DC Sputter System		Link Here	Download	Download	(Deputy) Ms. Chang Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail : changcw@mx.nthu.edu.tw (Deputy) Ms. Kuo	Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail: changcw@mx.nthu.edu.tw	Link Here
	RF Sputter System	NTHU Lab Cleanroom	<u>Link Here</u>	Download	Download	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail: kuowenfeng@hotmail.com (Deputy) Ms. Chang	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail: kuowenfeng@hotmail.com	Link Here
g Pocess	Lithography Area in NTHU Lab Cleanroom A. Wet Bench (2 Sets) B. Spin Coater	NTHU Lab	<u>Link Here</u>	A Download B Download C Download		Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290 E-mail : sungmy@mx.nthu.edu.tw	Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290 E-mail : sungmy@mx.nthu.edu.tw	Link Here
Wet Etching Pocess Tools	C. Hot Plate & Hood Chemical area in NTHU Lab (Station I & Station III)	Cleanroom	Link Here	Download	Download	(Deputy) Ms. Kuo Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail : changcw@mx.nthu.edu.tw	Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298	<u>Link Here</u>

		- 1						
						Mr. Sung TEL: 03 - 5742290 or NTHU Ext. 42290 E-mail : sungmy@mx.nthu.edu.tw	E-mail: changcw@mx.nthu.edu.tw	
<u> </u>		_						
Dry Etching Pocess Tools	Reactive Ion Etcher (RIE)	NTHU Lab Cleanroom	Link Here	<u>Download</u>	Download	Mr. Sung TEL: 03 - 5742290 or NTHU Ext. 42290 E-mail : sungmy@mx.nthu.edu.tw	Mr. Sung TEL: 03 - 5742290 or NTHU Ext. 42290 E-mail : sungmy@mx.nthu.edu.tw	Link Here
						(Deputy) Ms. Kuo		Link Here Link Here Link Here Link Here
	EVG610 Double Side Aligner		<u>Link Here</u>	<u>Link Here</u>	<u>Link Here</u>	Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290 E-mail : sungmy@mx.nthu.edu.tw	Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290 E-mail : sungmy@mx.nthu.edu.tw	<u>Link Here</u>
						(Deputy) Ms. Chang		
	DLP Maskless Exposure System					Ms. Cheng TEL: 03 - 5715131 Ext. 33313 E-mail : cnmm1015@gmail.com	Ms. Cheng TEL: 03 - 5715131 Ext. 33313	
		NTHU Lab	<u>Link Here</u>	<u>Download</u>	Download	(Deputy) Dr. Sun-Zen Chen Ext. 42285 E-mail: szchen@mx.nthu.edu.tw	E-mail : <u>cnmm1015@gmail.com</u>	Link Here
sols	EVG620	Cleanroom	<u>Link Here</u>	Download	Download	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail : kuowenfeng@hotmail.com	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail : <u>kuowenfeng@hotmail.com</u>	Link Here
y To						(Deputy) Mr. Sung		
Lithography Tools	NX2000 Nano Imprint System		Link Here	Download		Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290 E-mail : sungmy@mx.nthu.edu.tw	Mr. Sung TEL: 03 - 5742290 or NTHU Ext.42290	Link Here
_						(Deputy) Ms. Tai	E-mail : <u>sungmy@mx.nthu.edu.tw</u>	Link Here Link Here
	E have lither words Contain	R130 in	12-1-11			Ms. Cheng TEL: 03 - 5715131 Ext. 33313 E-mail : cnmm1015@gmail.com	Ms. Cheng TEL: 03 - 5715131 Ext. 33313	
	E-beam lithography System	NTHU Lab	<u>Link Here</u>	<u>Download</u>	Download	(Deputy) Dr. Sun-Zen Chen Ext. 42285 E-mail: szchen@mx.nthu.edu.tw	E-mail : <u>cnmm1015@gmail.com</u>	<u>Link Here</u>
s	O₂ Plasma Cleaning System		Link Here	Download	Download	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail: kuowenfeng@hotmail.com	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299	Link Here
T00	3 ,	NTHU Lab				(Deputy) Ms. Tai	E-mail : <u>kuowenfeng@hotmail.com</u>	
Other Tools	RTP	Cleanroom	<u>Link Here</u>	Download	Download	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291	Link Here
						(Deputy) Mr. Sung	E-mail : <u>wury@mx.nthu.edu.tw</u>	

UV & Ozone Dry Stripper	<u>Link Here</u>	Download	Download	Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail: changcw@mx.nthu.edu.tw (Deputy) Ms. Kuo	Ms. Chang TEL: 03 - 5742298 or NTHU Ext. 42298 E-mail: <u>changcw@mx.nthu.edu.tw</u>	<u>Link Here</u>
∝-step (Surface profiler System)	<u>Link Here</u>	Download		Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail: kuowenfeng@hotmail.com (Deputy) Ms. Cheng	Ms. Kuo TEL: 03 - 5742299 or NTHU Ext. 42299 E-mail : <u>kuowenfeng@hotmail.com</u>	<u>Link Here</u>
Spectroscopic Ellipsometer	<u>Link Here</u>		Download	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail: wury@mx.nthu.edu.tw (Deputy) Ms. Tai	Ms. Wu TEL: 03 - 5742291 or NTHU Ext. 42291 E-mail : <u>wury@mx.nthu.edu.tw</u>	Link Here

1141202 update

【Characterization Instrument List & Charges】

	acterization instrument List & Charges 1						
Туре	Instrument	Location	Introduction	Service Request	Technician Contact Information	Examiner Contact Information	Charge
	Field Emission Scanning Electron Microscope (JSM-7000F)		<u>Link Here</u>	Download	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail: <u>yhtai@mx.nthu.edu.tw</u>	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail: yhtai@mx.nthu.edu.tw	<u>Link Here</u>
edo	Field Emission Scanning Electron Microscope (JSM-IT800)	R131 in NTHU Lab	<u>Link Here</u>	Download	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : <u>yhtai@mx.nthu.edu.tw</u>	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : <u>yhtai@mx.nthu.edu.tw</u>	<u>Link Here</u>
	High Vacuum Scanning Probe Microscope (SPM)	R132 in NTHU Lab	Link Here	Download	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : yhtai@mx.nthu.edu.tw	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : yhtai@mx.nthu.edu.tw	Link Here
Electron N	High Resolution Transmission Electron Microscope (HRTEM)	R110 in Materials Science Laboratory	<u>Link Here</u>	Download	Ms. Lai 03 – 5715131 Ext. 42287/31032 E-mail: siyilai@mx.nthu.edu.tw	No self - operation	Link Here
	Dual-beam Focused Ion Beam System (FIB) (Zeiss Crossbeam System)	R122 in NTHU Lab	<u>Link Here</u>	Download	Ms. Lai 03 – 5715131 Ext. 42287/31032 E-mail: <u>siyilai@mx.nthu.edu.tw</u>	Ms. Lai 03 – 5715131 Ext. 42287/31032 E-mail: <u>siyilai@mx.nthu.edu.tw</u>	<u>Link Here</u>
	Dual-beam Focused Ion Beam System (FIB) (FEI Helios Nanolab 600i System)	R122 in NTHU Lab	<u>Link Here</u>	Download	Ms. Lai 03 – 5715131 Ext. 42287/31032 E-mail: <u>siyilai@mx.nthu.edu.tw</u>	Ms. Lai 03 – 5715131 Ext. 42287/31032 E-mail: <u>siyilai@mx.nthu.edu.tw</u>	Link Here
olar Cel	Solar Simulator (Service Suspended)		<u>Link Here</u>	Download	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : yhtai@mx.nthu.edu.tw	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : yhtai@mx.nthu.edu.tw	<u>Link Here</u>
	Incident Photon Conversion Efficiency (IPCE) (Service Suspended)	R132 in NTHU Lab	<u>Link Here</u>	Download	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail: yhtai@mx.nthu.edu.tw	Ms. Tai TEL: 03 - 5742292 or NTHU Ext. 42288/35332/42292 E-mail : yhtai@mx.nthu.edu.tw	Link Here

E-Gun Evaporation System (I)

[Instrument introduction]

Back to [Instrument List]

1. Brand Model: ULVAC



2. Application

The system can deposit Al · Ti · Au · Pt · Cu · Cr metal film.

3. Equipment Specifications

- Power supply: Maximum 300 W •
- Substrate heating: 0~300 °C ∘
- Operating pressure: < 8*10⁻⁶ torr •
- Crucible size: 10 cc •

X Notices

The chamber can accept 4 inch (12 pieces) or 6 inch (3 pieces) and if your wafer size less than 4 inch, please use the heat resistant tape to fix your sample on the 4-inch wafer.

We can accept the maximum deposit film 800nm thickness.

For the process procedure include from load the sample in the chamber and wait the process temperature down to the room temperature and then finish pump down procedure

The Center support metal source include Ti · Al · Cu · Cr.

We can help customer do the ODM to deposit Au . Pt film.

We will charge from this form. (The costs of materials are listed below.)

Instrument	List	of Charge	NTHU	Acade	mics	Industry	
	-	Cu · Al	NTD 75/hr NTD		D 115/hr	NTD 150/hr	
	Common	Cr · Ti	NTD 150/hr	NT	D 200/hr	NTD 300/hr	
	List of	Charge	NTHU			OTHERS	
E-gun I		Au	NTD 5,843/	NTD 5,843/g		NTD 7,304/g	
(Consumable cost for E-		Pt NTD 3,0		<mark>′g</mark>		NTD 3,750/g	
gun I)	Noble metal	• The the • The	ces are subject to change according to market rates thou t prior notice. The costs of noble metals are calculated by measuring the used weight with the unit of a gram. The costs of common metals are basing on the pocessing time, and the maximum charge is up to 4				
	The user sh	ould check th	e integrity of both the	source mat	erial and t	the crucible with the	

corresponding technician when he/she borrows the target as well as turns it back. Any damages to the target will certainly transfer the charge to the user.

E-Gun Evaporation System (I)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

(VIP discount): The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.
- Note 4: The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.

Instrument/ List of	Charge	NTHU	Academics	Industry	
E-Gun Evaporation System I		NTD 25/min	25/min NTD 37/min NTD 50/min		
(The processing time includes the time of vacuuming, depositing, and cooling.			ne consumable will additionally ased on the use of material.		
The necessary charge hours are 2 hours.)	Charge of Self-Operating	NTD 12/min	NTD 18/min	NTD 24/min	

E-Gun Evaporation System (II)

[Instrument introduction]

1. Brand: FSE



2. Application

Evaporation of oxide film by E-gun

3. Specifications

- Operating pressure: < 6.5*10⁻⁶ torr
- Wafer Size: 4 inch Wafer*4 or 6 inch Wafer*4; If it is chip, it must be fixed on Wafer fist by your-self.
- Provide material types: $SiO_2 \cdot Al_2O_3 \cdot TiO_2$

Back to [Instrument List]

E-Gun Evaporation System (II)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

(VIP discount): The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

		ge	NTHU	Acad	lemics	Industry			
	E-Gun Evaporation System II				NTD 25/min	NTD	37/min	NTD 50/mii	n
	(The processing time includes the time of vacuuming, depositing, and cooling. The necessary charge hours are 2 hours.)		ma			e consumable will additionally ased on the use of material.			/
				Charge of Self-Operating	NTD 12/min	nin NTD 18/min N		NTD 24/mii	n
	Instrum	ent/ List of Charge		NTHU	Academics		In	Industry	
	E-gun II	SiO2		NTD 75/hr	NTD :	113/hr		NTD 150/hr	
	Material	Al2O3		NTD 100/hr	NTD :	150/hr		NTD 200/hr	
	Charge	TiO2		NTD 125/hr	NTD :	188/hr		NTD 250/hr	

Polymer Deposition System (PDS)

[Instrument introduction]

[Instrument List]

1. Brand and model: PDS2010



2. Application

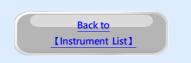
Parylene coating

3. Specifications

- Parylene C · N · D
- Wafer size :4" \ 6" wafer and chip
- Cavity volume 4"wafer *9 or 6"wafer *3

Polymer Deposition System (PDS)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

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(VIP discount): The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Ch	NTHU	Academics	Industry	
Polymer Deposition System (PDS)				
(The processing time includes the time of vacuuming, heating, depositing, and cooling. The necessary charge hours are 8 hours.)	Charge of	NTD 11/min	NTD 16/min	NTD 22/min

SAMCO PECVD System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: Samco PD-220N



2. Application

For SiO₂ (SiH₄ + N₂O) & Si₃N₄ (SiH₄ + NH₃+N₂) Deposition ; TEOS-Oxide(Characterization service only) $\,^{\circ}$

3. Specifications

• Wafer size: chin~ 4" silicon wafer • (size over 4" please contact with the technician first)

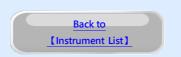
RF Power: <200W

• Temperature: < 300 °C •

• Uniformity: < 5 % •

SAMCO PECVD System

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

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[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List o	of Charge	NTHU	Academics	Industry
SAMCO PD-220N	Charge of manufacturing service	NTD 25/min	NTD 37/min	NTD 50/min
(The processing time includes the	manadetaring service			
time of depositing and cleaning. The necessary charge hours are 2 hours.)	Charge of Self-Operating	NTD 11/min	NTD 16/min	NTD 22/min

DC Sputter System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: ULVAC Co. Japan (Vacuum system: ULVAC Mechanical pump & ULVAC Cryo pump 16P)



2. Application

Sputtering Ti · Pt · Ni · Cu · Ag · W · Au · Al · Cr · Mo

3. Important specifications

- Process gas: Ar
- Wafer size: 4 inch silicon wafer, maximum 8 wafers per run •
- Power supply: maximum 100 ~ 300 W •
- Operating pressure: 8* 10⁻⁶ torr •

X Note :

This equipment could accept break wafers (please attach it onto a 4 inch full wafer.)

Please describeyour target thickness and materials, and draw the cross-sectional view of your wafer on the application form.

Precious metal will be charged depends on used weigh, and the charge should be paid right after usage by cash. Please check the metal charge standard below.

Instrument	List of Charge		NTHU	Academics		Industry		
		Cu · Al	NTD 150/10min	NTD 200/10min		NTD 250/10min		
	Common	Cr · Ti	NTD 250/10min NTD 38		0/10min	NTD 500/10min		
	metal	W · Ni	NTD 400/10min	NTD 55	0/10min	NTD 700/10min NTD 1,000/10min		
		Ag	NTD 600/10min	NTD 800/10min		NTD 1,000/10min		
	List of	Charge	NTHU			OTHERS		
DC Sputter (Consumable	Noble	Au	NTD 5,843	<mark>8/g</mark>		NTD 7,304/g		
cost for DC	metal	Pt	NTD 3,000	<mark>)/g</mark>		NTD 3,750/g		
Sputter)	For a sta material	ndard manufacturi cost for a customiz	e according to market raing ng service, the charge of zed service is basing on the re calculated by measur	f consumable is the process.	up to 30 mi			

- The user should check the integrity of both the source material and the crucible with the corresponding technician when he/she borrows the target as well as turns it back. Any damages to the target will certainly transfer the charge to the user.
- The noble metals are not allowed to borrow. If you want to deposit the noble metal film via DC Sputter, please send a request for a manufacturing service.

DC Sputter System

[Service & Charge]



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[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of C	Charge	NTHU	Academics	Industry	
DC Sputter System	Charge of	NTD 25/min	NTD 37/min	NTD 50/min	
(The processing time includes the time of vacuuming, depositing, and cooling. The necessary charge hours are 2.5 hours and 3 hours for manufacturing service and self-operating respectively.)	manufacturing service	The cost of the consumable will additionally charge based on the use of material.			
	Charge of Self-Operating	NTD 8/min	NTD 12/min	NTD 16/min	

RF Sputter System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and Model: ULVAC RFS-200S



2. Purpose

Sputter deposition of TiO₂, TIN, Ti on the substrate

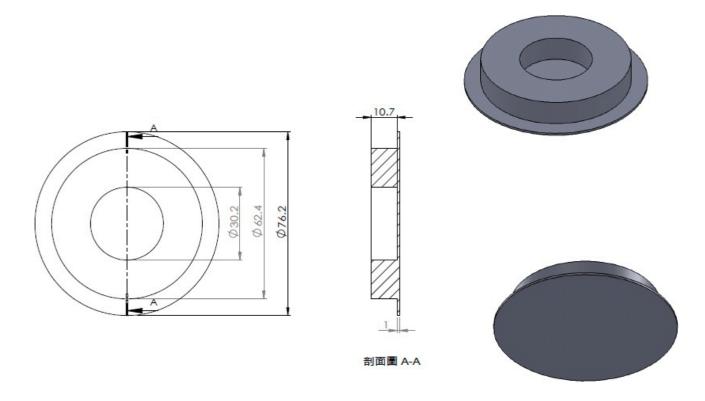
3. Specifications

- Sputtering power supply: RF: 50~300W, DC pulse: 60-300W
- Main pump: CRYO pump
- Ultimate chamber pressure: 1*10-6TORR
- Uniformity: 4" wafer: < 5%
- This equipment is a single chip process: 4 inch*1 or 1 inch*6 (Choose one to use)
- The maximum flow rate of nitrogen and oxygen is 30 sccm
- The machine has a bias function (the upper limit of use must be lower than 150 V)
- The machine has a heating function (the upper limit of use must be lower than 350 °C)

XNotice:

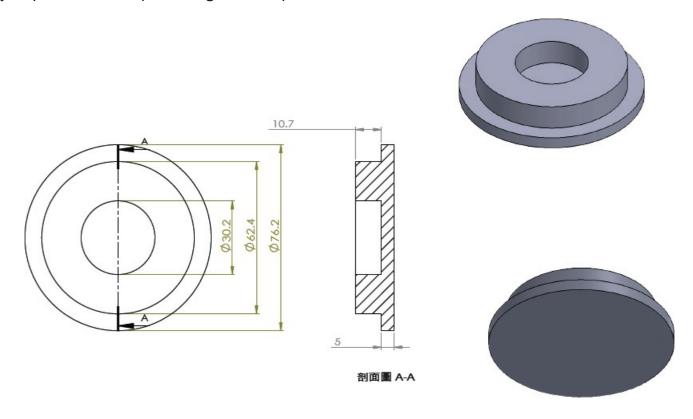
- 1. This machine is a research experimental machine and the users need to prepare their own targets.
- 2. The use of equipment includes vacuum relief and sample input + process + cooling + sample retrieval + vacuum establishment. After that, the users can log out of the system.
- 3. Please do not leave the site during the manufacturing process (not including cooling).
- 4. There is only one-piece Ti target in the center. Please register with the administrative Ms. Wan-Chin Chuang if you want to borrow the target material.

The specifications of the copper backplane are as follows



If you use the copper backplane provided by the center, you need to order a 3-inch round target with a thickness of 4 mm.

If you purchase one-piece targets, the specifications are as follows:



RF Sputter System

[Service & Charge]



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Instrument/ List of C	Charge	NTHU	Academics	Industry
RF Sputter System (The processing time includes the time of vacuuming, cooling, and operating time.	Charge of manufacturing service	NTD 25/min	NTD 37/min	NTD 50/min
Minimum usage hours: entrusted operation: 2 hrs self-operation: 2.5 hrs)	Charge of Self-Operating	NTD 10/min	NTD 15/min	NTD 20/min

Field Emission Scanning Electron Microscope

(JSM-IT800)

[Instrument introduction]

Back to
[Instrument List]

1. Brand: JSM-IT 800 (Semi-In-Lens) •



2 · Application

- Surface structures inspection on the samples such as metal, ceramics and polymer, etc.
- Energy Dispersive Spectrometer (EDS) is capable of detecting elements, provides a qualitative identification and semi-quantitative analysis.

3 · Specification

Voltage: 0.5 to 30 KV °

Magnification: 30 to 500000 °

Resolution: 0.8nm (15 KV) \ 0.7 nm (1KV) \ 3.0 nm (15KV, 5 nA) \circ

Note: Magnetic materials are prohibited from being placed in the device

4 · Auto Fine Coater

The JEOL Smart Coater (JEC-3000FC) is a fully automated sputter coater that applies a fine grained gold or platinum (option) coating on samples for imaging in a scanning electron microscope.



5 · Air Isolated Transfer System

JEOL has built a special air-lock system that can handle the transfer of air-sensitive specimens to be imaged in the SEM without atmospheric exposure. Applications include: components in rechargeable batteries, fuel cells, and catalysts among others. Any exposure to oxygen or moisture in the air can completely alter or destroy the structure of these highly reactive materials.

Transfer vessel



Field Emission Scanning Electron Microscop (JSM-IT800)

[Service & Charge]

Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note:

- 1. The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.
- 2. The fee schedule has been effective since May 15, 2025.

Instrument/ List of Charge		NTHU	Academics	Industry		
Field Emission Scanning		NTD 2,400/hr	NTD 3,500/hr	NTD 5,500/hr		
Electron Microscope	Charge of Characterization Service	【Fee of report】				
(The necessary charge hour	Characterization service	An additional NTD2	000 is required for CNMM formal			
is 2 hour for manufacturing		report.				
service and self-operating respectively.)	Charge of Self-Operating	NTD 1,500/hr	NTD 2,500/hr	NTD 4,500/hr		
(The necessary charge hours are 2 hours for visiting activites.)	transfer vessel	1600 each time				
	Auto Fine coater	NTD 200/10mins	NTD 300/10mins	NTD 400/10mins		

Lithography Area in NTHU Lab Cleanroom

[Wet Bench (2 Sets) & Spin Coater & Hot Plate & Hood]

Back to [Instrument List]

[Instrument introduction]

1. Brand and Model



2. Equipment Specifications

Wafer should be less than 6 inches (including 6 inches wafer)

X Attention

- If the experiment contains metal or Acetone, please operate on the left half of cleaning bench (operation in the right half of cleaning bench is prohibited). The right half of cleaning bench is used for lithography process. (The area operated by the two cleaning benches, the left half area is operated metal and the right half area is operated by lithography process).
- Acidic chemicals and alkaline chemicals are prohibited to operate in the cleaning bench.
- All areas in the lithography laboratory are shared. Please do not place personal laboratory appliance.
 If you do not apply to place chemicals or private laboratory appliance, confiscate appliance and charge the relevant fees.
- After using the chemical waste solution, please use the recycling system to recover.

[Service & Charge]

From 2024/06, all NTHU Lab Cleanroom users should pay the cleanroom facility charge as entering the cleanroom.

The corresponding fees:

800 NT/day for each person for the Lithography area (A day is defined from 00:00 to 23:59.) 400 NT/day for each person for the Chemical area

cleanroom except the regions of Lithography area and Chemical area.)

100 NT/day for each person for the White-light area (The White-light area is the area within the

If the user has used any instruments in the specified area, the cleanroom facility charge will be removed automatically. For example, if a student uses an instrument located in the White-light area, then the expense of the White-light area will not be calculated. If he uses an instrument located in the Lithography area, then the costs of White-light area and Lithography area will be canceled.

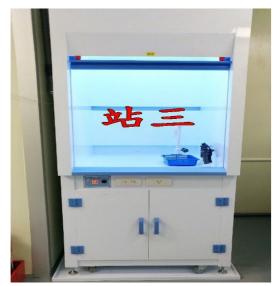
Chemical Area in NTHU Lab [Station I & Station II & Station III]

[Instrument introduction]

Back to
[Instrument List]

1. Model





2. Application

Cleaning, Wet etching

3. Specifications of wafer

4", 6", and broken wafer can be used in the Cleanroom.

Cleaning the 4" wafer can borrow the wafer cassette from Miss. Zhuang at CNMM, but cleaning the 6" and broken wafer needs to bring your own wafer cassette.

X Precautions

- Using the chemical station needs to wear protective equipment and aware of rules and regulations.
- Please write the record book before use, using without record will have a severe penalty.
- Before using sulfuric acid to remove photoresist at station 2, need to use acetone and DI water clean the wafer first.
- To prevent chemical cleaning bench pollution and safety consideration, use DI water clean the bench before the next process.
- Station 3 is only used as auxiliary space for users of Station 1 and Station 2. (Everyone takes turns to use it after coordination.)
- No one is allowed to use chemicals at Station 3.
- To avoid penalties for violations, please read the manual beside the b or the latest version manual on the website before the operation.
- Please bring your own gas mask.

Chemical Area in NTHU Lab [Station | & Station | | & Station | |]

[Service & Charge]



Instrument/	List of Charge	NTHU Academics		Industry
Chemical Area (Minimum foundry	Charge of manufacturing service	NTD 20/min	NTD 25/min	NTD 30/min
working time is 1hr) (Daily billing for self- operating)	Charge of Self-Operating	NTD 400/day	NTD 400/day	NTD 400/day

^{*} The 4" wafer cleaning stander of OEM is use H2SO4 and BOE cleaning. Other cleaning processes must discuss the feasibility with the manager, the fee will cost additional.

Back to [Instrument List]

[Service & Charge]

Preferential schemes:

Generous discount : The professor/advisor who prepay 50,000 NT can have a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 35% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
	Charge of manufacturing service			

Surface profiler System

[Instrument introduction]

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[Instrument List]

1. Model: DektakXT



2. Purpose

Two-dimensional surface profile measurement and analysis

Three-dimensional measurement analysis (not open to use), if you have special needs, please contact the manager to discuss.

3. Specifications

Stage Size	Max:6 inch
Force	1-10mg
Tip radius	2 μm
Vertical range	smaller than 1mm
Measurable minimum depth	Nano-scale film
and height	
Sample thickness	50 mm
Scan range	55 mm
Camera	3.1 million pixel
Step repeatability	1 sigma at 1000 Å, the standard step film must
	be less than 4 Å,

XNotice:

- If the material is soft, you can set Stylus Force to 1.
- If the size of measured sample is smaller than 2*2 cm, please stick it on the large-size blank by yourself.

Surface profiler System

[Service & Charge]



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Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

(VIP discount): The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
Surface profiler System (The minimum charge of manufacturing service is 1 hr)	Charge of manufacturing service		25 NTD/min	30 NTD/min
	Charge of Self-Operating	10/ min	15 NTD/min	20 NTD/min

[Instrument introduction]

Back to
[Instrument List]

[Service & Charge]



Preferential schemes:

Generous discount : The professor/advisor who prepay 50,000 NT can have a 50% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 70% discount on self-operating and a 35% discount on manufacturing service.

- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
manufa	Charge of acturing service			
Sel	Charge of f-Operating			

Spectroscopic Ellipsometer

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: JA Woollam (Model: M2000)



2. Purpuse

Measure the film thickness in a non-contact, non-destructive way.

3. Specifications

- (1) Measuring spectrum range: 2 45nm 1000nm
- (2) Light source: 75-watt xenon lamp
- (3) Measurement method: With automatic variable measurement angle, the measurement angle can be set through the computer, and the incident angle range is from 45 degrees to 90 degrees
- (4) stage form: $200 \text{mm} \pm 10 \text{mm}$ sample table size, movement stroke: X- the Y are both $100 \text{mm} \pm 10 \text{mm}$; with vacuum suction horizontal platform, need comprise a vacuum pump
- (5) measuring thickness range: 5 nm to 5 μm
- (6) Substrate types: Si, Glass, Quartz, stainless steel
- (7) Types of thin film materials: organic polymer materials, nitrides, semiconductor materials, dielectric materials, metal materials, etc.

4. Measurable items

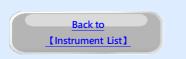
- (1) Film thickness
- (2) Optical constants of the film or substrate material (ex: refractive index n, extinction coefficient k)
- (3) Film surface roughness
- (4) Multilayer materials

5. Attention

- (1) The recommended size of the test piece is larger than 2*2cm2
- (2) The currently open self-operated and measurable films are: SiO2, SiNx, Ta2O5, Al2O3, SiC; please contact the administrator for other films to be measured.

Spectroscopic Ellipsometer

[Service & Charge]



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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
Spectroscopic Ellipsometer (Clean process and operating time are	Charge of manufacturing service		NTD 35/min	NTD 45/min
included in the billing, the minimum usage time is 1hr)	Charge of Self-Operating	NTD 15/min	NTD 25/min	NTD 35/min

[Instrument introduction]

─ \ Brand and model:

 \sqsubseteq \cdot Applications

 $\Xi \cdot \text{Important specifications}$

X Notification

Back to [Instrument List]

[Service & Charge]

Preferential schemes:

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Instrument/ List of Charge		NTHU	Academics	Industry
	Charge of manufacturing service			
	Charge of Self-Operating			

Reactive Ion Etcher (RIE)

[Instrument introduction]

1. Manufactory & Model: CNT-RPA08



2. Applications

Etch Silicon base

3. Important specifications

RF Power: 50~300W,13.56 MHz •

Gas: CF4 \ SF6 \ CHF3 \ O2 \ Ar \(\cdot \)

Main pump: Turbo pump

Process pressure : 5~300 mTorr •

※ Note

• Wafer size: 1*1 cm² ~ 6-inch Full wafer

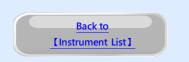
• Etching mask : PR · Silicon oxide · Silicon nitride · Cr · Al

• The wafer CAN NOT contain Au, Cu, Pt, Fe, Co, Ni...etc. and its oxide.

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[Instrument List]

Reactive Ion Etcher (RIE)

[Service & Charge]



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- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
Reactive Ion Etcher (RIE) (The processing time includes the time	Charge of manufacturing service	NTD 25/min	NTD 37/min	NTD 50/min
of etching and cleaning. The necessary charge hours are 1 hours.)	Charge of Self-Operating	NTD 12/min	NTD 18/min	NTD 24/min

Back to
[Instrument List]

[Instrument introduction]

- ─ · Brand and model :

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 $\Xi \cdot Specifications$

•

Back to [Instrument List]

[Service & Charge]

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Instrument/ List of Charge		NTHU	Academics	Industry
	Charge of manufacturing service			
	Charge of Self-Operating			

DLP Maskless Exposure System

[Instrument introduction]

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[Instrument List]

1. Manufactory & Model: ARMS (Japan) / UTA-IIIA



2. Specialities

- Because the lamp source is LED, you can exposure immediately without lamp pre-heating.
- DLP resolution is 1280 x 1024 pixels.
- Exposure process do not need the Mask.
- The pattern edit function is included in software.
- The min. line width can $\leq 3\mu m$ depend on the lens magnification and PR.
- The single-side alignment accuracy limited on lens.
- The XY movement stage range is 75mm x 50mm.

X Notation

• Process relative materials (ex. PR) should be prepared by yourself.

DLP Maskless Exposure System

[Service & Charge]



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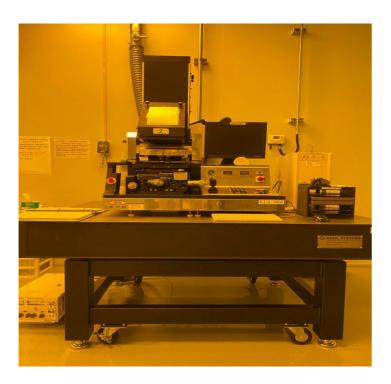
- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.
- Note 4: The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.

Instrument/ List of Charg	NTHU	Academics	Industry	
DLP Maskless Exposure System (The minimum charge time is 1 hr. including	Charge of manufacturing Service		NTD 75/min	NTD 100/min
"Spin, Baking, Startup , Shutdown and Process")	Charge of Self-Operating	NTD 32/min	NTD 48/min	NTD 64/min

[Instrument introduction]

Back to
[Instrument List]

1. Brand Model: EVG620



2. Application

Pattern transfer process

3. Important Specifications

- Wafer size: Si wafer(1~4inch) · Thickness between 0.1~2 mm
- Mask size: 5 inch mask size and the mask thickness must less than 4 mm
- Range of alignment: X, Y, Z: +/- 5 mm; Rotation Theta: +/- 3.5°
- Alignment accuracy: Mask aligner: 0.5um for top side alignment (With 20X obj)
- Exposure mode: soft contact, hard contact, vacuum contact
- Mercury lamp light source: Standard lamp power 350W.
- Exposure Intensity: 10mw/cm²
- Standard NUV for 350 450nm

XNotification

Please prepare the demanded photoresist by yourself. CNMM only sells EPG512 and AZ4620 (Both of them are positive tone photoresist.)

[Service & Charge]



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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ Lis	t of Charge	NTHU	Academics	Industry
EVG620 (The processing time includes the time of spin coating, baking, aligning,	Charge of manufacturing service	NTD 50/min	NTD 75/ min	NTD 100/ min
exposing, and lamp cooling. The necessary charge hours are 2 hours.)	Charge of Self-Operating	NTD 26/min	NTD 39/ min	NTD 52/ min

NX2000 Nano Imprint System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: Nanonex / NX2000



2. Applications

Use hot pressing or illumination imprint to transfer the pattern.

3. Important specifications

Imprint mode: Thermal curing, UV curing 4 inch wafer or broken sample

Pneumatic pressurization : 0~600 psi

• Heating range of hot pressing: RT~200 ℃

• 500 W Mercury lamp light source: 320~390 nm

X Notification

• User can contact with the center if need some help with the process flow.

NX2000 Nano Imprint System

[Service & Charge]



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- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
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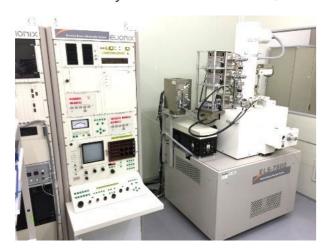
Instrument/ List of Charge		NTHU	Academics	Industry
NX2000 Nano Imprint System (The processing time includes the time of spin coating, imprinting, and	Charge of manufacturing service			
turing on and off process. The necessary charge hours are 2 hours.)	Charge of Self-Operating	NTD 10/min	NTD 15/min	NTD 20/min

E-beam Lithography System

[Instrument introduction]

Back to
[Instrument List]

1. Manufactory & Model: ELIONIX INC. /ELS-7800



2. Applications

Use electron beam direct writing to transfer the designed circuit layout onto the specimen.

3. Important specifications

- Voltage: 80KeV
- Electric beam current: 10pA ~ 600pA
- Minimum line width: 20nm (Tool resolution capability), 50nm (positive resist, 80-nm thickness), 70nm (positive resist, 200-nm thick
- Substrate size: 2 inch~6 inch full wafer or square specimen (specimen should be larger than 10x10mm² but smaller than 30x30mm²

X Precautions

• The substrate should be electrically conductive. If not, a conductive layer is required. Please ask when request for a foundry service.

E-beam Lithography System

[Service & Charge]



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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Note 4: The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.

Instrument/ List of Charge			NTHU	Academics	Industry
	manufacturing	Basic Operation	NTD 3,000/2hrs	NTD 4,500/2hrs	NTD 6,000/2hrs
E-beam lithography system	service	Charge Counted	NTD 25/min	NTD 37/ min	NTD 50/ min
The minimum charge time is 2 hrs.	Self-	Basic Operation	NTD 2,880/2hrs	NTD 4,320/2hrs	NTD 5,760/2hrs
.521113.	Operating	Charge Counted	NTD 24/ min	NTD 36/ min	NTD 48/ min

[Note]

- 1. The qualification for operating this equipment is primarily for doctoral students or dedicated assistants. If there is a need for self-operation but the laboratory has no doctoral students or dedicated assistants, an application can be submitted to the center. After evaluation by the center, the advisor can assign one master student as the representative of the laboratory. Once licensed, the student can operate the equipment independently, but only one master student is allowed per laboratory..
- 2. Those who operate the machine by themselves or join the membership must be trained 5 times, and they can use the machine only after passing the assessment.
- 3. After obtaining the self-operation qualification, every six months, there must be record of use in order to renew the operation.

O₂ Plasma Cleaning System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: SAMCO · Model PC-300



2. Applications

PR etch

3. Important specifications

• Wafer size: Piece wafer \ 4" wafer (max 12 piece) \ ~ 8" wafer (max 3 piece) \ \ •

• Power supply: Maximum 300 W •

• Gas : Ar \ O₂ \

• Main pump: Rotary pump •

O₂ Plasma Cleaning System

[Service & Charge]



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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
O₂ Plasma Cleaning System	Charge of manufacturing service	NTD 20/min	NTD 30/min	NTD 40/min
(The processing time includes				
the time of etching and cleaning. The necessary charge hour is 1 hour.)	Charge of Self-Operating	NTD 10/ min	NTD 15/min	NTD 20/min

RTP System

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: Premtex RTP-S61-M



2. Applications

Carrier Disk Type	Annealing Material	Gas
Carrier A:SiC Pollution-free Process	Oxide/nitride/siliconetc.	All
Carrier B:Graphite (with cover) Dirty Process	Metal structure/Ⅲ-V compoundsetc	NO O2

Note

- 1. Prohibit organic/low melting point/volatile materials.
- 2. The carrier B belongs to dirty process, so be sure to cover it when operating the system
- 3. Please select the "correct" carrier when using to avoid chamber contamination.
- 4. Handle the carrier carefully.

If you have any questions about the above, please contact us.

3. Specifications

Wafer size: Piece wafer \ 4" wafer \ 6" wafer

Maximal Ramping Speed:

- 40°C/sec for Graphite
- 30°C/sec for SiC

Process Temperature:200~1000°C

Maximal Process Time:

- T<500°C:10min
- T<800°C:5min
- T<1000°C:3min

Process Gas:

- N2 3SLM/ N2 30SLM
- O2 500SCCM/ Ar 500SCCM

RTP System

[Service & Charge]



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Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of	NTHU	Academics	Industry	
RTP System (The processing time includes the	Charge of manufacturing service	NTD 20/min	NTD 30/min	NTD 40/min
time of vacuuming, heating, annealing and cooling. The necessary charge hour is 1 hour.)	Charge of Self-Operating	NTD 10/min	NTD 15/min	NTD 20/min

UV & Ozone Dry Stripper

[Instrument introduction]

Back to
[Instrument List]

1. Brand and model: SAMCO UV-1



2. Applications

Wafer surface cleaning

3. Important specifications

• Applicable for III-V wafer and wafer which contains metals.

• Gas : O2

UV & Ozone Dry Stripper

[Service & Charge]



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Instrument/ List of Charge		NTHU	Academics	Industry
UV & Ozone Dry Stripper The processing time includes the time of heating,	Charge of manufacturing service	NTD 17/min	NTD 25/min	NTD 34/min
stripping/etching, and cooling. The necessary charge hour is a half-hour.)	Charge of Self-Operating	NTD 3/min	NTD 5/min	NTD 6/min

Field Emission Scanning Electron Microscope (JSM-7000F)

[Instrument introduction]

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[Instrument List]

1. 廠牌型號:

Brand: JSM-7000F, JAPAN ELECTRON OPTICS LABORTARY CO., LTD. (JEOL) .



2. Application

- Micro structures inspection on the various samples such as metal, ceramics and polymer, etc.
- An additional component of energy dispersive spectrometer (EDS) of X-ray provides a quantitative identification and semi-quantitative analysis of sample elements.

3. Specification

Voltage : 0.5 to 30 KV •

• Magnification : 30 to 250000 •

Resolution: 1.2 nm (30 KV) \ 1.5 nm (15 KV) \ 3.0 nm (1KV) \.

4. Auto Fine Coater

The JEOL JFC-1600 Auto Fine Coater is designed to coat non-conductive specimens, such as biological specimens primarily for use in scanning electron microscope with high efficiency within a short time.



Field Emission Scanning Electron Microscope (JSM-7000F)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.
- Note 4: The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.

Note5: The fee schedule has been effective since May 15, 2025.

Instrument/ List of Charge		NTHU	Academics	Industry
Field Emission Scanning			Use JSM-IT800	
Electron Microscope	Charge of Characterization Service	【Fee of report】		
(The necessary charge hour	Characterization service	An additional NTD2000 is required for CNMM formal		
is 1 hour for manufacturing		report.		
service and self-operating respectively.)	Charge of Self-Operating	NTD 1,000/hr	NTD 2,000/hr	NTD 3,600/hr
(The necessary charge hours are 2 hours for visiting activites.)	Auto Fine coater	NTD 200/10mins	NTD 300/10mins	NTD 400/1 0 mins

[Instrument introduction]

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[Instrument List]

[Service & Charge]



Preferential schemes:

Generous discount : The professor/advisor who prepay 50,000 NT can have a 50% discount on self-operating charges and a 20% discount on manufacturing service.

(VIP discount): The professor/advisor who prepay 500,000 NT can have a 70% discount on self-operating and a 35% discount on manufacturing service.

- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

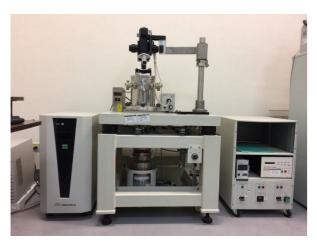
Instrument/ List of Charge		NTHU	Academics	Industry

High Vacuum Scanning Probe Microscope (SPM)

[Instrument introduction]

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[Instrument List]

1. Brand: SEIKO SPA-300HV



2. Specification

(1) Hardware control system

- Scan speed: $0.05 \sim 125 \, \text{Hz}$; nm $\sim \mu \text{m/sec}$
- Scan rotation: 360 degree (± 0.1degree)
- Bias on the sample ±10V •
- Control resolution: X-Y:18 bits DAC ± 200V; Z:21 bits DAC ± 200V °

(2) Scanner: 20 um scanner

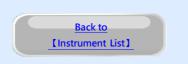
- Scan area: horizontal nm~20um, vertical: ~1.6um
- resolution≤0.2nm , vertical resolution≤0.01nm ∘
- sample size ≤ 35mm dimension 1 cm x thickness 10mm ∘
- Manual mechanical movement range: ± 2.5 cm.

3.. 儀器功能

- 1. Atomic Force Microscope (AFM)
- 2. Dynamic Force Microscope (DFM)
- 3. FFM (Friction Force Microscopy)
- 4. Vector Scan (Lithography)
- 5. MFM (Magnetic Force Microscopy)
- 6. PFM (Piez Response Microscopy)
- 7. KFM (Kelvin Force Microscopy)
- 8. (Conductive-AFM)

High Vacuum Scanning Probe Microscope (SPM)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

- Note 1: Please pay the overdraft first before you want to attend the preferential scheme.
- Note 2: You can use your preferential scheme until the prepayment is run out.
- Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of C	harge	NTHU	Academics	Industry
		NTD 1,500/hr	NTD 2,250/ hr	NTD 3,000/ hr
High Vacuum Scanning Probe Microscope (The necessary charge hours are	Charge of Characterization Service	The processing time includes the time of pretreatment, measuring, and data processing.		
2 hour and 2 hours for manufacturing service and self- operating respectively.)		[Fee of report] An additional NTD report.	02000 is required fo	or CNMM formal
operating respectively,	Charge of Self-Operating	NTD 750/ hr	NTD 1,125/ hr	NTD 1,500/ hr
Probe Cost		Self-suppli	ed or purchased fr	rom CNMM

^{*}Probe Cost: NTD 800/piece (Self-supplied or purchased from CNMM)

High Resolution Transmission Electron Microscope (HRTEM)

[Instrument introduction]

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[Instrument List]



1. Model: JEOL JEM-F200

2. Performance

Acceleration voltage : 200KV and 80KV •

• Type: Cold Field Emission Gun •

TEM Point resolution: 0.19nm@200KV •

TEM lattice resolution: 0.10nm@200KV and 0.14nm@80KV -

• STEM Lattice resolution: 0.14nm@200KV and 0.31nm@80KV •

• STEM Detectors : DF, BF(ABF) and BEI •

Double tilted holder •

High Resolution Transmission Electron Microscope (HRTEM)

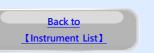
[Service & Charge]



Instrument/ List o	NTHU	Academics	Industry	
High Resolution Transmission Electron Microscope	Charge of Characterization Service	N	TD 18,000/pic	
(The necessary charge hours are 3 hours.)	Charge of Self-Operating	No self- operating	No self- operating	No self- operating

Dual-beam Focused Ion Beam system (FIB)

[Instrument introduction]





1. Model: FEI Helios Nanolab 600i System

2. Application

- For TEM specimens preparation
- Nano structure manufacturing
- Deposition for circuit repair
- Cross-section observed

3. Performance

	SEM	FIB			
Acceleration voltage	350V -30 KV	500V -30 KV			
Probe current	0-22 nA	1.1 pA - 65 nA			
Resolution	< 0.9 nm (15 KV)	< 4 nm (30KV)			
Resolution	< 1.4 nm (1 KV)				
GIS	Pt				
Omniprobe 200					
Energy Dispersive Spectrometer (EDS)					

4. Self-operating license

- Restricted to doctoral students and postdoctoral researchers, who have license to use scanning electron microscopes. Eligible students/researchers can register through the contact below.
- Registration contact: Miss. Zhuang, CNMM of Tsinghua University (Room 519, Tsinghua University-Innovation Incubation Building, ext. 42266, ntmc8000@my.nthu.edu.tw).
- After training and qualify, you can get a self-operating license.
- After obtaining the self-operating license, the users are responsible for damages due to operational errors caused by the users.

Dual-beam Focused Ion Beam system (FIB) [Service & Charge]

Instrument/ Lis	t of Charge		NTHU	Academics	Industry
	Charge of	General user	NTD2,000/hr	NTD 3,500/hr	NTD 6,000/hr
	Charge of Characterization Service	VIP user	Prepayment of 100,00 20% off disc	, ,	Prepayment of 300,000 NT, you get a 20% off discount.
Dual-beam Focused Ion Beam System (FIB)		General user	A 25% off discount of 2,000 NTD/hr	No self- operating	No self- operating
(Characterization service: The necessary charge hours are 3 hours. The charge is calculated by the unit of an hour when the using time exceeds the necessary charge hours. Self-operating: The	Charge of Self-Operating	VIP user	【Prepayment of 100,000 NT, you get a 40% off discount.】 【Prepayment of 300,000 NT, you get a 50% off discount.】	No self- operating	No self- operating
hours. Self-operating: The necessary charge hours are 3 hours. The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.) Consum		le cost	Depositing platinum deposition time is no additionally charged 10 time ex	ot over 6 minute	s. Or it will be ninute when the

If Auto Fine Coater is necessary due to the poor conductivity, please refer to the charge of Field Emission Scanning Electron Microscope (JSM-IT800) of CNMM.

Solar Simulator

[Instrument introduction]

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[Instrument List]

1. Brand: Oriel class A, 91160A, Newport Corporation

Solar simulation is used to measure the photoelectric conversion of solar cells.

The intensity of standard solar is defined as 100 mW/cm2 AM 1.5G. Standard solar cell is supported to calibrate the intensity of solar simulator before measurement $^{\circ}$



2. Specification

• Simulator Type: Full Spectrum Solar Simulator •

• Lamp Type: 300 W Xenon, Short Arc •

• Beam Size: 2 x 2 in. (51 x 51 mm) •

Collimation: <±10° °

Solar Simulator

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
Solar Simulator	Charge of Characterization Service	NTD 750/hr	NTD 1,125/hr	NTD 1,500/hr
(The necessary charge hour is 1 hour.) Charge of Self-Operating	NTD 400/hr	NTD 600/hr	NTD 800/hr	

Incident Photon Conversion Efficiency (IPCE) [Instrument introduction]

1. Brand: ENLI, EQE-D-3011, ENLI Technology Co., Ltd

IPCE (Incident Photon-to-electron Conversion Efficiency) is the conversion ratio of the incident photon to electron by a photovoltaic cell.



2. Specification

- Wavelength range: 350-1100 (nm) •
- Wavelength interval: adjustable, 1-50(nm), (Default 5 nm) •
- Chopping frequency: adjustable, (4~5 kHz, MCU controlled) •
- Auto Jsc calculation with reference solar spectrum or consumer input
- S/N ratio > 500 •
- Precision, error bar: < 2% •
- Repeatability: > 95% •
- Light Bias: Optional component •
- Voltage Bias: Optional component •
- Rapid: $< 4 \, \text{min}$ for one trip measurement, 300-1100 nm \circ
- Lamp lifetime: QTH lamp-2000hrs •

Incident Photon Conversion Efficiency (IPCE)





Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Cha	NTHU	Academics	Industry	
Incident Photon Conversion Efficiency	Charge of Characterization Service	NTD 750/hr	NTD 1,125/hr	NTD 1,500/hr
(The necessary charge hour is 1 hour.)	Charge of Self-Operating	NTD 400/hr	NTD 600/hr	NTD 800/hr

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[Instrument introduction]

1. Brand Model: EVG610



2. Application

Pattern transfer process

3. Important Specifications

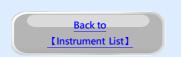
- Wafer size: 4-inch or 6-inch Full wafer. Thickness between 0.1~10 mm.

 (If the substrate is not a full wafer, please stick it on 4-inch or 6-inch full wafer.)
- Mask size: 5-inch or 7-inch mask. the mask thickness must less than 4 mm
- Exposure platform uniformity: 6-inch full wafer range ≤ 3%
- Thickness 1 μm photoresist resolution (soft contact mode): Single line ≤ 3μm
- Top-side alignment accuracy: ±1 μm
 (Top side microscope movement range X: 32~150 mm; Y: -75~30 mm)
- Bottom-side alignment accuracy: ±2 μm
 (Bottom side microscope movement range X: 30~100 mm; Y: -10~10 mm)
- Exposure mode: proximity, soft contact, hard contact, vacuum contact
- LED exposure Intensity: 35 mw/cm²

XNotification

Please prepare the demanded photoresist by yourself. CNMM only sells EPG512 and AZ4620 (Both of them are positive tone photoresist.)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

(VIP discount): The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

Note 1: Please pay the overdraft first before you want to attend the preferential scheme.

Note 2: You can use your preferential scheme until the prepayment is run out.

Note 3: The preferential scheme is only used for the charges of self-operating, and manufacturing service excludes the consumables, license charges, and others.

Instrument/ List of Charge		NTHU	Academics	Industry
EVG610 (The processing time includes the time of spin coating, baking, aligning	Charge of manufacturing service	NTD 50/min	NTD 75/ min	NTD 100/ min
and exposing. The necessary charge hour is 1 hour.)	Charge of Self-Operating	NTD 26/min	NTD 39/ min	NTD 52/ min

E-Gun Evaporation System (III)

[Instrument introduction]

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[Instrument List]

1. Brand and model: EGION TE20001



2. Application

E-gun evaporate the Al, Ti, Au, Pt, Cr etc. metal films(Nonopen to use self-provided crucible and source), and you can choose to clean sample surface by ion source before depositing.

3. Specifications

(1) Operating pressure: < 3*10⁻⁶ torr

(2) Evaporate rate: 1 A/s(3) Crucible size: 15 c.c.

(4) 4-inch wafer(at most 6wafer), or 6-inch wafer(at most 4 wafer)

(5) Fragment should be fixed on 4-inch or 6-inch wafer. (A wafer can be bought in the center. 800 TWD for one 4-inch wafer.)

Metal charging standards:

Equipme	service		NTHU	Other academic		Industry		
nt name				circles				
e-gun III	General	Al	NT\$150/10		10min	NT\$250/10min		
target	metal		min					
material		Cr \ Ti	NT\$250/10	NT\$250/10 NT\$380/10		NT\$500/10min		
expenses			min					
	service		NTHU			OTHERS		
	Precious	Au	NT\$5843/10min		NT	<mark>\$7304/10min</mark>		
	metal	Pt	NT\$3000/10min		NT\$3000/10min N		<mark>NT</mark>	\$3750/10min

- 1. The upper limit of OEM materials charge is 30min, exclusive of special OEM charge.
- 2. The above is reference price, and the actual price is adjusted according to the fluctuation of the material.
- 3. The amount of grams used is according to the actual weighing. If the weighing is less than 1 gram, please count it as 1 gram.
- 4. Prices are subject to change according to market rates without prior notice.

If the target material is damaged, the user shall be fully liable for compensation, so please confirm the target material with the assistant when taking it out or returning it.

E-Gun Evaporation System (III)

[Service & Charge]



Preferential schemes (Effective Date: October 10, 2025):

Generous discount: The professor/advisor who prepay 100,000 NT can have a 30% discount on self-operating charges and a 20% discount on manufacturing service.

[VIP discount]: The professor/advisor who prepay 500,000 NT can have a 50% discount on self-operating and a 30% discount on manufacturing service.

[Note 1]

Those who want to enjoy the latest preferential program must have no debts.

[Note 2]

The pre-payment has no expiration date; however, when the payment is used out, it will cost the original price.

[Note 3]

The advance payment is for special funds only; the discount does not include consumables and access fees.

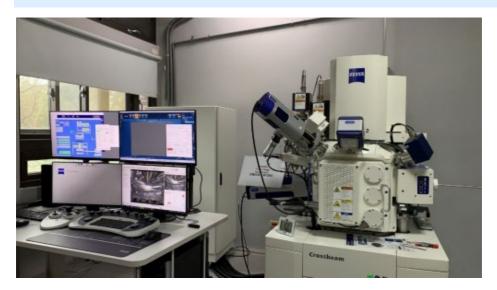
[Note 4]

After exceeding the minimum usage time, billing will be made every 15 minutes.

Instrument/ List of	NTHU	Academics	Industry	
E-Gun Evaporation System III	Charge of	NTD 40/min	NTD 60/min	NTD 80/min
(Vacuuming, cooling and operating time are included in the billing, and the minimum usage time is 2hr)	manufacturing service	Material fee is extra		
	Charge of Self-Operating	NTD 20/min NTD 30/min NTD 40/mi		NTD 40/min

Zeiss Crossbeam FIB system [Instrument introduction]

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[Instrument List]



1. Model: Zeiss Crossbeam System

2. Application

- For TEM specimens preparation
- Nano structure manufacturing
- Deposition for circuit repair
- Cross-section observed
- EDS: Identification and quantification of the elements present in a sample
- EBSD: Analysis of the crystallographic orientation and microstructure of crystalline materials

3. Performance

	SEM	FIB				
Acceleration voltage	350V -30 KV 500V -30					
Probe current	0-22 nA	1 pA – 100 nA				
GIS	Pt/C					
	Omniprobe 400					
En	ergy Dispersive Spectrometer (EDS					
Electron Backscatered Diffraction (EBSD)						
Cryo stage (Not open)						

4.Self-operating license

- Restricted to doctoral students and postdoctoral researchers, who have license to use scanning electron microscopes. Eligible students/researchers can register through the contact below.
- Registration contact: Miss. Zhuang, CNMM of Tsinghua University (Room 519, Tsinghua University-Innovation Incubation Building, ext. 42266, ntouchar.org/ntouchar.org/ ntouchar. All the statement of the statement
- After training and qualify, you can get a self-operating license.
- After obtaining the self-operating license, the users are responsible for damages due to operational errors caused by the users.

Zeiss Crossbeam FIB system 【Service & Charge】



Instrument/ Lis	t of Charge		NTHU	Academics	Industry
	Charge of	General user	NTD2,500/hr	NTD 4,500/hr	NTD 7,500/hr
	Characterization Service	VIP user	Prepayment of 100,000 NT, you get a 20% off discount.		Prepayment of 300,000 NT, you get a 20% off discount.
Zeiss Crossbeam FIB System (Characterization service: The		General user	A 25% off discount of 2,500 NTD/hr	No self- operating	No self- operating
necessary charge hours are 3 hours. The charge is calculated by the unit of an hour when the using time exceeds the necessary charge hours. Self-operating: The necessary charge hours are 3 hours. The charge is calculated by the unit of 15 minutes when the using time exceeds the necessary charge hours.)		VIP user	【Prepayment of 100,000 NT, you get a 40% off discount.】 【Prepayment of 300,000 NT, you get a 50% off discount.】	No self- operating	No self- operating
	Consumabl	le cost	Depositing platinum on the sample is free when deposition time is not over 6 minutes. Or it will additionally charged 100 NT for each minute whe time exceeds 6 minutes. Depositing carbon on the sample is charged 300 for each time.		s. Or it will be ninute when the
	Lift-out Cu grid		NT 200 for each		

If Auto Fine Coater is necessary due to the poor conductivity, please refer to the charge of Field Emission Scanning Electron Microscope (JSM-IT800) of CNMM.